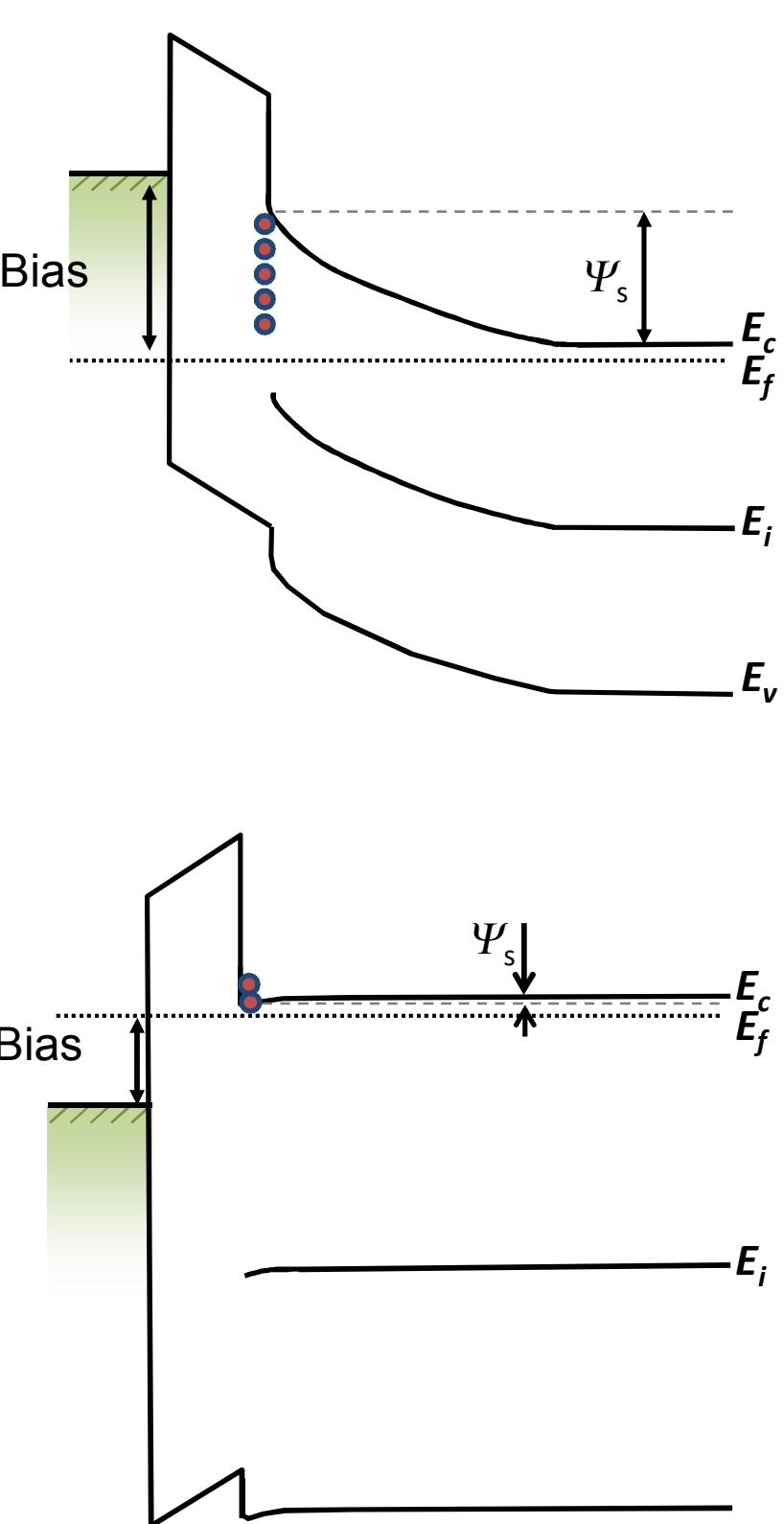


Reliable High-Performance Gate Oxides for Wide Band Gap Devices

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Motivation

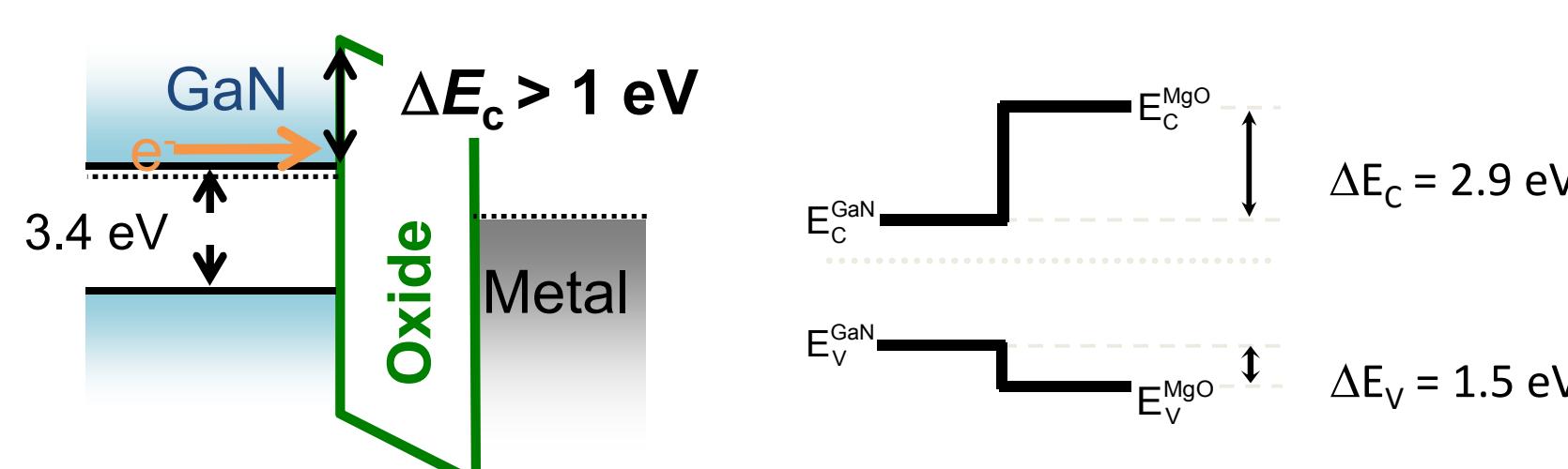
- Wide band gap semiconductor devices can improve the performance of energy conversion systems
- Voltage control, normally-off devices based on GaN have seen limited deployment
- Lack of deployment stems from issues related to switching stability/repeatability/reliability and conduction
- All of these issues are related to defects in the insulating component of the device (gate oxide/passivation layer)

FY16 Activities

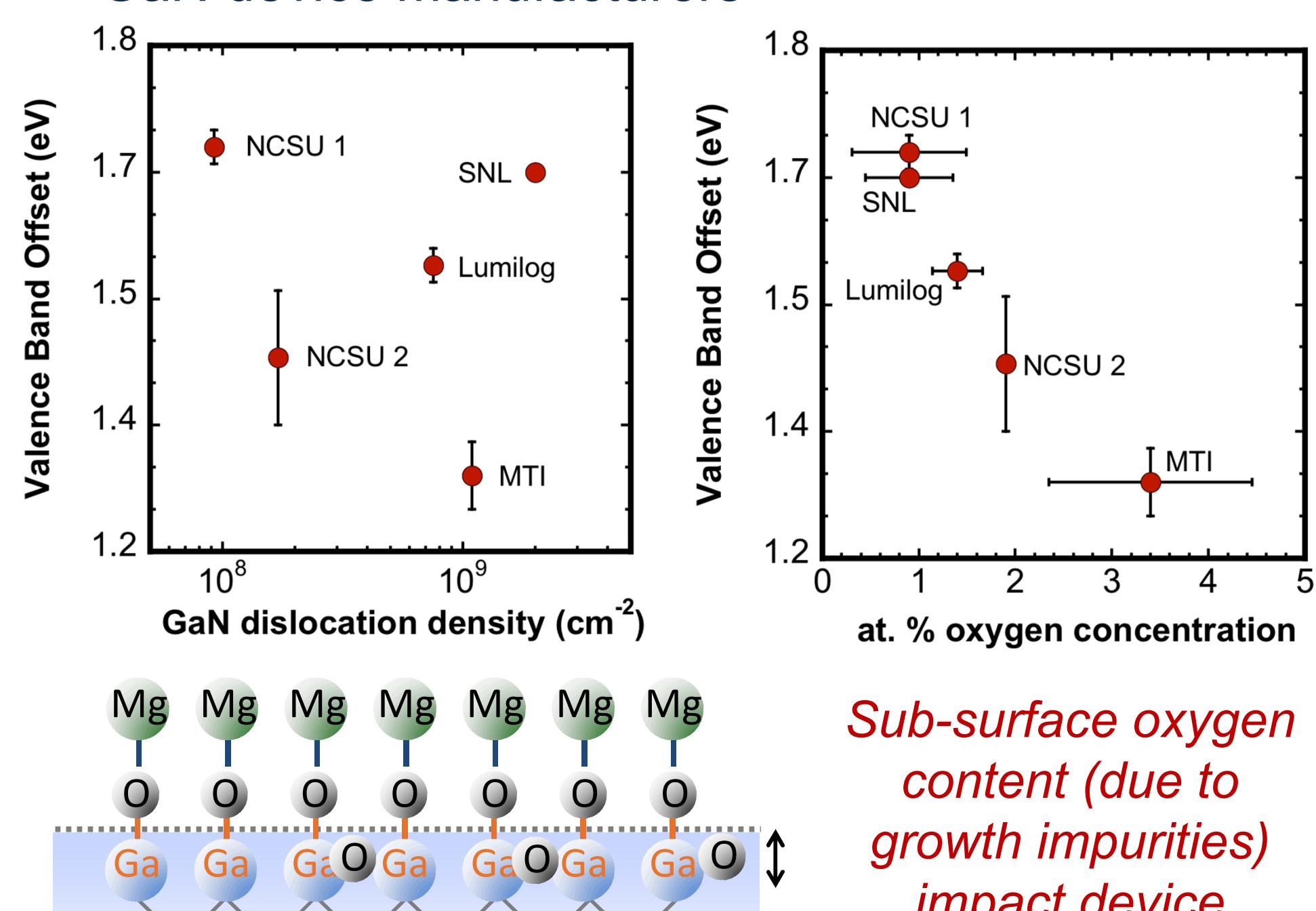
- Quantify GaN defect/composition effects on MgO/GaN electronic structure
- Quantify and verify interface trap density at MgO/GaN
- Prepare lattice matched MgO-CaO alloys on GaN
- Establish collaboration with external industrial partner

GaN Defect Effects on Electronic Structure

- Band offsets are an important factor in device design
 - Insulation resistance
 - Threshold voltage
- Typically require ≥ 1 eV at both conduction and valence band



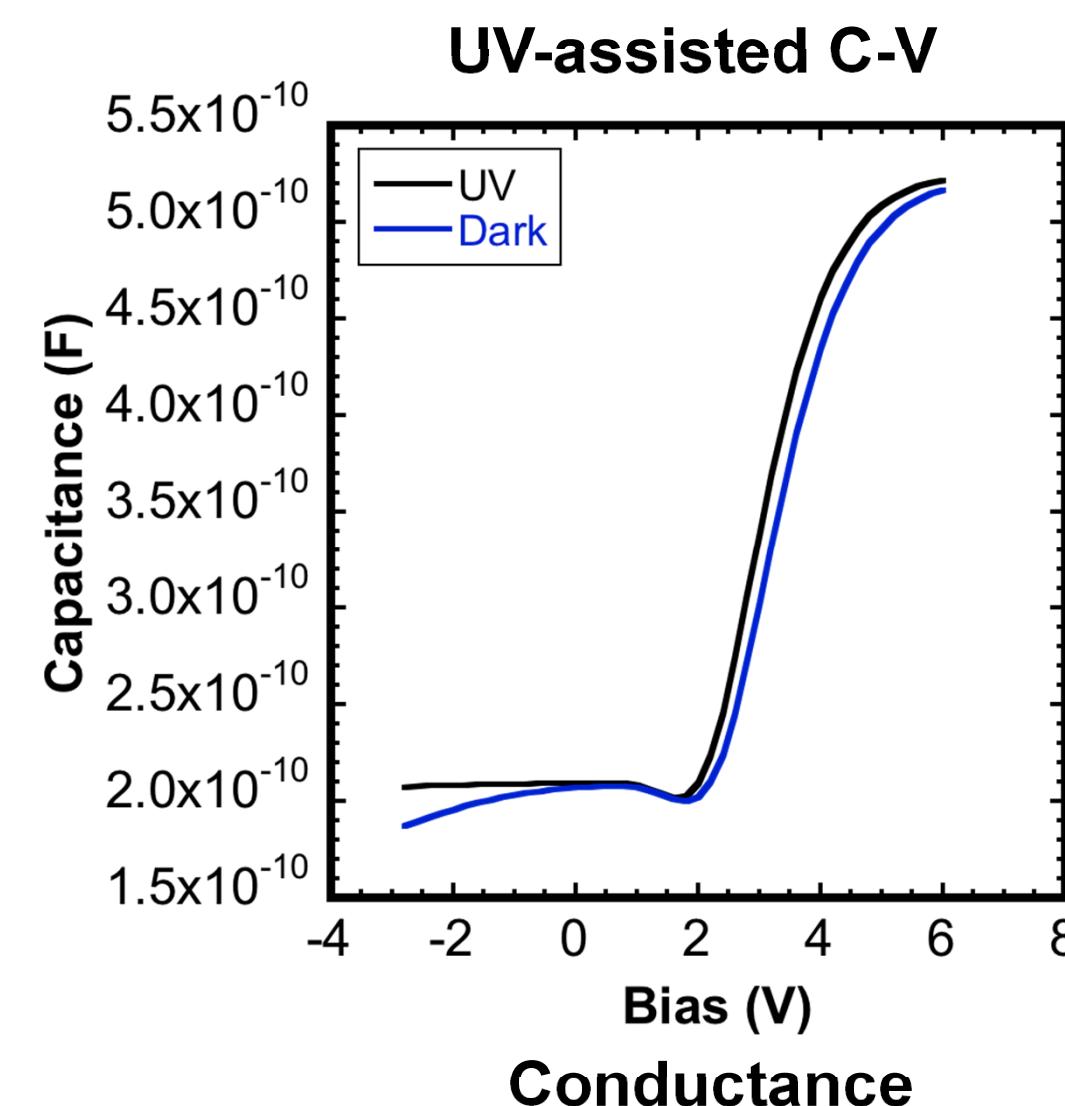
- Band structure measured using X-ray photoelectron spectroscopy (XPS) in molecular-beam grown MgO/GaN
- Surface oxygen content measured with XPS
- Dislocation density measured with X-ray diffraction
- Several sources of GaN were investigated to identify design principles needed for different GaN device manufacturers



- GaN dislocation density does not strongly impact band offsets
- GaN near-surface oxygen impurity content strongly affects band offsets
- Source of GaN material will strongly impact device performance**
- GaN properties must be known prior to device design**

Electronic Properties: MgO/GaN

- MgO (18 nm)/GaN ($N_d \approx 2 \times 10^{18} \text{ cm}^{-3}$) devices prepared and C-V and conductance characteristics measured
- UV-assisted C-V technique utilized
 - Provides one of the most conservative and complete measures for D_{it}

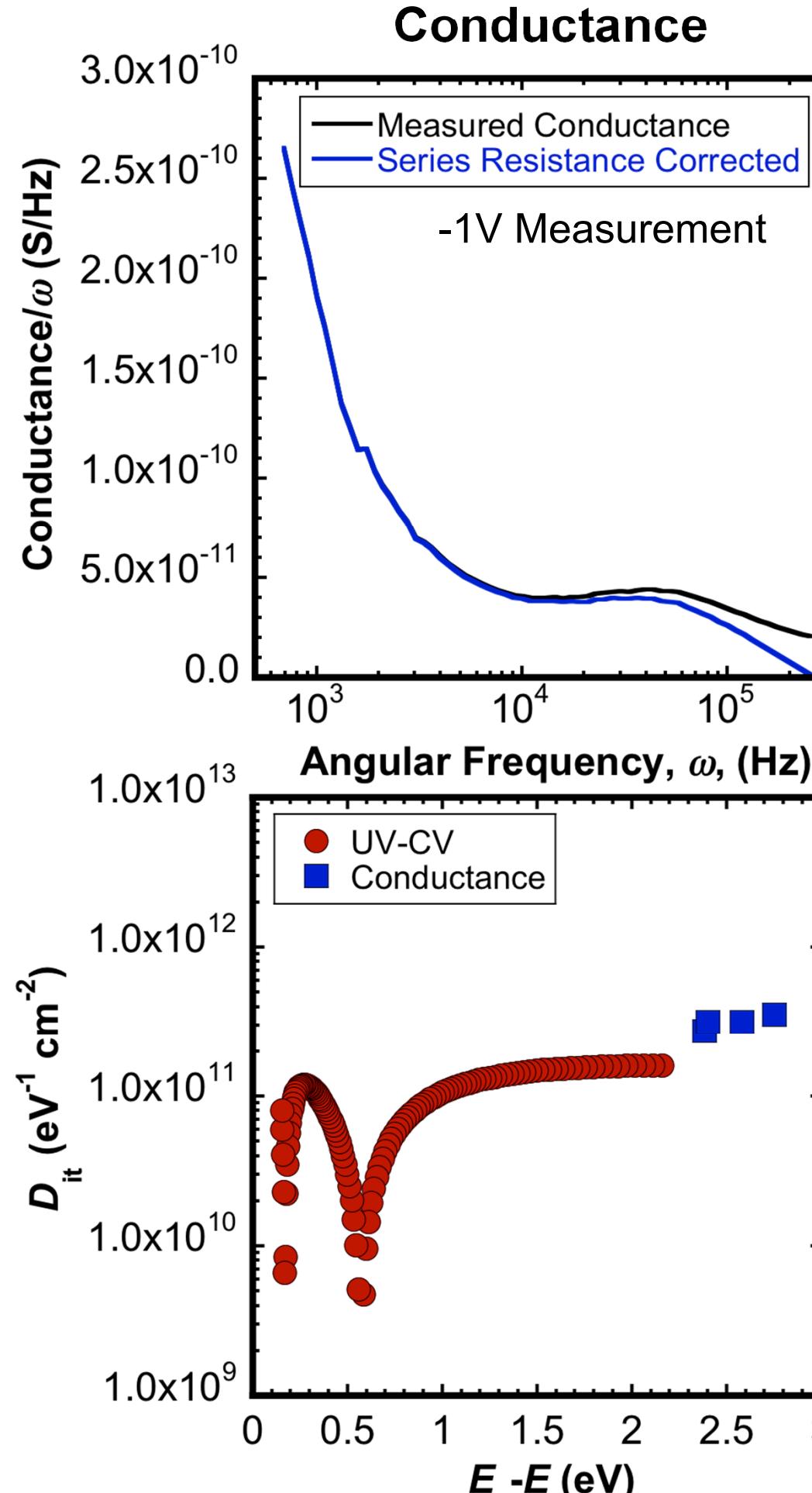


Average D_{it} across band gap:

$$D_{it} = \frac{C_{ox}}{qA} \left(\frac{\Delta V}{E_g} \right)$$

MgO D_{it} : $1.5 \times 10^{11} \text{ eV}^{-1} \text{ cm}^{-2}$

This is a very low (and promising) interface state density number. Such a low value requires verification by another technique

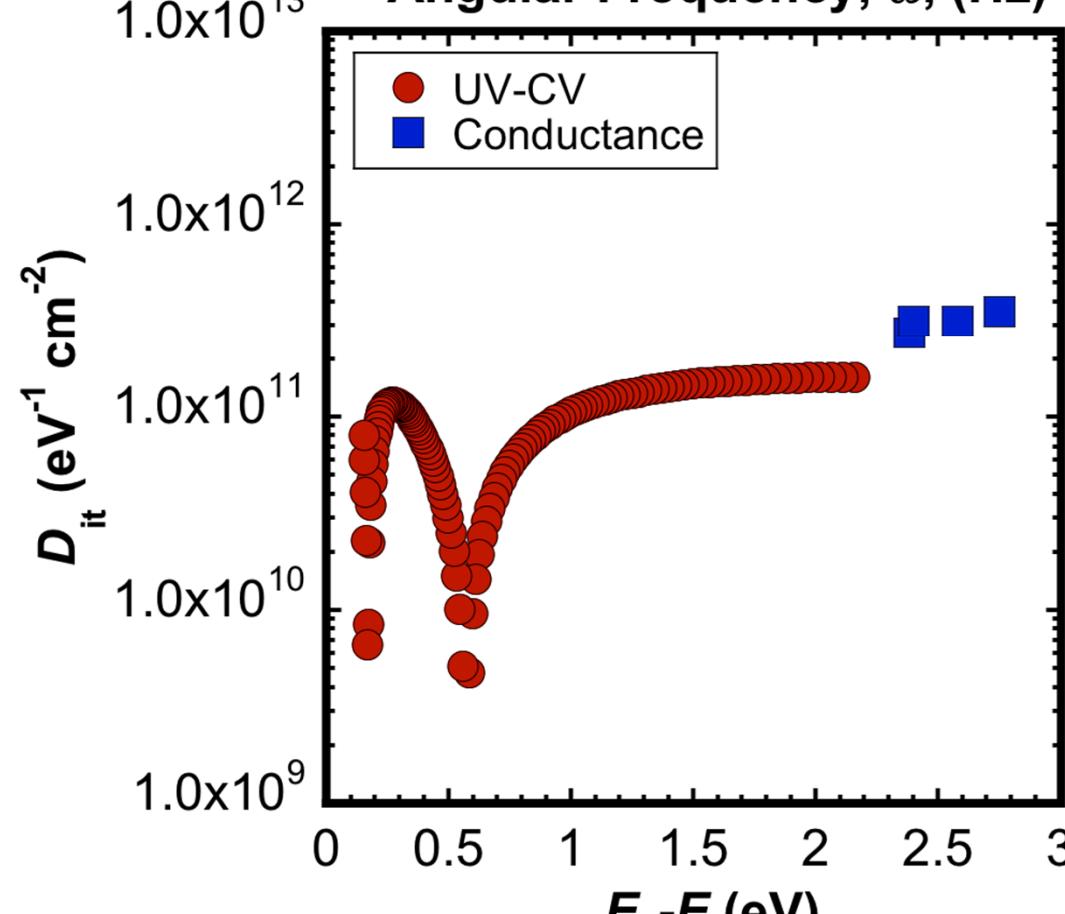


D_{it} at each bias/position in band gap:

$$D_{it} = \frac{2.5}{qA} \left[\frac{G}{\omega} \right]_{max}$$

MgO D_{it} : $3 \times 10^{11} \text{ eV}^{-1} \text{ cm}^{-2}$

Conductance technique verifies low interface state density values at MgO/GaN interface



⁷Wu, Y., Appl. Phys. Lett., **90**, 2007

⁸Sawada, T., Appl. Surf. Sci., **159-160**, 2000

⁹Mishra, U., J. Appl. Phys., **106**, 2009

¹⁰Ostermaier, C., Phys. Status Solidi C, **5**, 2008

- D_{it} values are among the lowest reported for a gate insulator on GaN and verified by 2 measurement methods
- Positive threshold voltages observed
 - Implications for safe (enhancement mode, normally off) operation

FY16 Publications and Impact

- Developing a new understanding of surface chemistry and impact on device properties (band offsets)
- Research presented at 2 conferences and 2 invited colloquia
- E.A. Paisley, M. Brumbach, A. Allerman, A. Armstrong, R. Kaplar, A. Baca, S. Atcitty, and J.F. Ihlefeld, "Spectroscopic investigations of band offsets of MgO/AlGaN heterostructures with varying AlN content," Applied Physics Letters, **107**, 102101 (2015)
- 2 publications in preparation
- Have shown and verified that MgO on GaN have among the lowest reported interface defect state densities**
 - Will minimize issues resulting in performance limitations in GaN enhancement-mode devices.

FY17 Goals and Milestones:

- Complete D_{it} study for lattice matched MgO-CaO on GaN and SiC
- Prepare lattice matched alloys on SiC and pursue device development with industrial partner

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